



XA-9387  
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Hitoshi TAKEUCHI

Appln. No.: 09/714,183

Group Art Unit: 2877

Filed: November 17, 2000

Examiner: R. Punnoose

For: ABERRATION MEASURING APPARATUS, ABERRATION MEASURING METHOD, PROJECTION EXPOSURE APPARATUS HAVING THE SAME MEASURING APPARATUS, DEVICE MANUFACTURING METHOD USING THE SAME MEASURING METHOD, AND EXPOSURE METHOD

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PRELIMINARY AMENDMENT FOR CONTINUED EXAMINATION

Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

Sir:

Prior to the commencement of continued examination,  
please amend the subject application as indicated below.

Amendments to the claims begin on page 2 of this  
paper.

Remarks begin on page 12 of this paper.